

Refine Search

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DEPOSITION	528869
CHAMBER	1949356
OFFSET	814348
DATA	3414229
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COMPUTER	1509662
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DIFFERENCES	548359
BETWEEN	10605052
MEASUREMENTS	488282
MEMOR\$3	0
((DEPOSITION ADJ CHAMBER) AND (OFFSET ADJ DATA ADJ STRUCTURE) AND (COMPUTER ADJ MEMOR\$3) AND (RESOLVE ADJ DIFFERENCES ADJ BETWEEN ADJ MEASUREMENTS)).PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD.	3

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Search:	<input type="text" value="L19"/> Refine Search	
<input style="width: 100px; height: 25px;" type="button" value="Recall Text"/>	<input style="width: 100px; height: 25px;" type="button" value="Clear"/>	<input style="width: 100px; height: 25px;" type="button" value="Interrupt"/>

Search History

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<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=NO; OP=OR</i>		
<u>L19</u> (deposition adj chamber) and (offset adj data adj structure) and (computer adj memor\$3) and (resolve adj differences adj between adj measurements)	3	<u>L19</u>
<u>L18</u> (deposition adj chamber) and (offset adj data adj structure) and (computer adj memor\$3) and (first adj parameter) and (second adj parameter)	3	<u>L18</u>
<u>L17</u> 5871805.pn.	2	<u>L17</u>
<u>L16</u> (deposit\$3 adj chamber) and (configur\$3) and (wafers) and (measur\$3 adj3 thickness adj3 wafer) and (pattern)	11	<u>L16</u>
<u>L15</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers)	34	<u>L15</u>
<u>L14</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (pattern adj5 thickness)	0	<u>L14</u>
<u>L13</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (wafer adj3 thickness)	0	<u>L13</u>
<u>L12</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (wafer adj3 thickness) and (pattern)	0	<u>L12</u>
<u>L11</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (wafer adj3 thickness) and (pattern)	0	<u>L11</u>
<u>L10</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (measur\$3 adj thickness) and (pattern)	0	<u>L10</u>
<u>L9</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (measur\$3 adj thickness) and (deposition adj pattern)	0	<u>L9</u>
<u>L8</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (measur\$3 adj thickness) and (pattern)	33	<u>L8</u>
<u>L7</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (thickness) and (pattern)	34	<u>L7</u>
<u>L6</u> (deposit\$3 adj chamber) and (configur\$3 adj3 parameter) and (wafers) and (thickness) and (pattern)	34	<u>L6</u>
<u>L5</u> (deposit\$3 adj chamber) and (configur\$3 adj parameter) and (wafers) and (thickness) and (pattern)	0	<u>L5</u>
<u>L4</u> (deposit\$3 adj chamber) and (configur\$3 adj parameter) and (wafers) and (measur\$3 adj thickness) and (pattern)	0	<u>L4</u>
<u>L3</u> (deposit\$3 adj chamber) and (configur\$3 adj parameter) and (wafers) and (measur\$3 adj thickness) and (deposition adj pattern)	0	<u>L3</u>
<u>L2</u> (deposit\$3 adj chamber) and (configur\$3 adj parameter) and (wafers) and (measur\$3 adj thickness)	0	<u>L2</u>
<u>L1</u> (deposit\$3 adj chamber) and (configur\$3 adj parameter) and (wafers) and (measur\$3 adj thickness) and (deposition adj pattern)	0	<u>L1</u>

END OF SEARCH HISTORY